# youCOMPARATIVE ANALYSIS OF CRYSTAL GROWTH USING MONTE CARLO SIMULATION WITHOUT IMPURITIES



#### PROPOSAL SUBMITTED TO

DEPARTMENT OF PHYSICS
TRI-CHANDRA MULTIPLE CAMPUS
INSTITUTE OF SCIENCE AND TECHNOLOGY
TRIBHUVAN UNIVERSITY, NEPAL

FOR THE PROJECT WORK OF BACHELOR OF SCIENCE (B.Sc.) IN PHYSICS

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Kathmandu March 15, 2025

## **DISCLAIMER**

I, Kripas Khatiwada, affirm that this project proposal, "Comparative Analysis of Crystal Growth Using Monte Carlo Simulation Without Impurities," is my original work unless stated otherwise. No part of this proposal has been plagiarized, and all sources have been properly cited and acknowledged.

I confirm that this project will be conducted in compliance with the rules and guidelines of the Department of Physics at Tri-Chandra Multiple Campus and Tribhuvan University, Nepal. I will adhere to scientific integrity and academic honesty throughout this research.

I acknowledge the consequences of any violation of these declarations and take full responsibility.

Student Signature:
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Supervisor Approval:
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## 1. TITLE OF THE PROPOSED PROJECT

Comparative Analysis of Crystal Growth Using Monte Carlo Simulation Without Impurities

#### 2. ABSTRACT

**Keywords**: Crystal Growth, Monte Carlo Simulation, Lattice Models, Thermodynamics, Kinetic Monte Carlo, Molecular Beam Epitaxy, Atomic Deposition, Simulation Validation, Growth Mechanisms

This project investigates the process of crystal growth through the use of Monte Carlo simulations in a pure system, free of impurities, to understand the fundamental mechanisms that govern atomic deposition on a lattice. The study focuses on modeling the behavior of atoms as they interact with the lattice and each other, simulating various thermodynamic conditions that influence the crystal's structure. By examining different growth patterns, such as faceted, dendritic, and layer-by-layer formations, this project aims to analyze how these patterns emerge and how they relate to thermodynamic and kinetic factors, including temperature, pressure, and deposition rates.

The project leverages the **Metropolis algorithm**, a cornerstone of Monte Carlo methods, to simulate the atomic interactions and energy exchanges occurring during crystal growth. This allows for an in-depth understanding of the processes that lead to the formation of different crystal morphologies, as well as the thermodynamic stability and kinetic behavior of the growing crystal. By incorporating these computational methods, the study provides valuable insights into the dynamics of crystal growth at the atomic level.

Additionally, the simulation results will be compared with experimental data from scientific literature to assess the accuracy and reliability of the simulation model. The comparison will serve to validate the simulation approach and offer a better understanding of how well Monte Carlo methods can replicate real-world crystal growth under varying conditions. Ultimately, this research will contribute to advancing the design and fabrication of materials with tailored properties, which is crucial for various technological applications, such as semiconductor manufacturing, optoelectronics, and nanotechnology.

#### 3. INTRODUCTION

## 3.1 Background

Crystal growth is a key process in material science where atoms or molecules are deposited onto a lattice structure, resulting in the formation of a crystalline solid. The process of crystal growth is governed by a variety of factors, including temperature, pressure, surface energy, and atomic interactions. These factors influence the structure, morphology, and properties of the resulting crystal, which are critical for applications across several high-tech industries. In particular, controlled crystal growth is essential for the fabrication of semiconductors, the development of optoelectronic devices, and advances in nanotechnology. Understanding how these factors influence crystal formation allows for the precise manipulation of material properties, enabling innovations in fields like electronics, photonics, and materials engineering.

## 3.2 Importance of Computer Simulation

Computer simulations play a crucial role in understanding the complexities of crystal growth, offering a means to explore the microscopic mechanisms that are difficult or even impossible to observe experimentally. By simulating atomic interactions and energy exchanges, scientists can study how crystals form, grow, and evolve over time. These simulations provide insights into various processes, such as nucleation, surface dynamics, and the influence of thermodynamic and kinetic factors on the final structure of the crystal.

Monte Carlo simulations, specifically, are widely used in material science due to their versatility in modeling complex systems. Through random sampling techniques, Monte Carlo methods allow for the approximation of solutions to complex problems by simulating a wide range of possible states and transitions within the system. This approach makes it possible to model and study the growth of crystals under different thermodynamic conditions, providing valuable insights into the factors that control their formation and properties. The ability to simulate crystal growth at the atomic level can help optimize the production of materials with desired characteristics, thus advancing technological progress in various scientific domains.

#### 3.3 Difference Between Monte Carlo and Kinetic Monte Carlo Simulation

Monte Carlo simulation is a stochastic method that utilizes random sampling to model crystal growth, allowing for the estimation of equilibrium properties. Kinetic Monte Carlo (KMC), on the other hand, is an extension that incorporates time evolution by considering transition rates

based on physical probabilities, making it more suitable for modeling dynamic growth processes. The key difference lies in the treatment of time: while Monte Carlo simulations focus on equilibrium states, KMC simulations model the time-dependent evolution of the system.

#### 4. MOTIVATION

Monte Carlo methods are powerful tools for simulating complex processes, offering efficiency and flexibility in modeling crystal growth under various conditions. These methods are ideal for approximating atomic deposition and crystal formation, which are essential for understanding material behavior at the atomic level.

By simulating crystal growth in pure systems, Monte Carlo methods help uncover the fundamental mechanisms involved, such as nucleation and surface roughness. This insight is crucial for developing advanced materials with tailored properties, such as those used in electronics and nanotechnology.

This project aims to deepen our understanding of crystal growth, which is key for creating materials with specific characteristics for a wide range of technological applications.

## 5. LITERATURE REVIEW

#### **5.1 Literature Review from Various Sources**

A detailed literature review will be conducted using resources from scientific journals, academic databases, and online platforms to explore the current understanding of crystal growth through simulation. Key areas of focus will include:

- Monte Carlo and Kinetic Monte Carlo Approaches: Several studies have explored the
  application of Monte Carlo methods in simulating crystal growth. A useful reference is
  the article on Monte Carlo simulations in materials science from <u>Springer</u>, which
  discusses the application of these techniques to model atomic interactions and crystal
  growth. Another notable source is <u>ResearchGate</u>, where multiple publications discuss
  the kinetic Monte Carlo method for simulating thin-film deposition and crystal growth.
- Lattice-Based Models for Thin-Film Deposition: The website <u>Materials Project</u>
  provides a rich database of crystal structures and material properties that can be
  modeled using lattice-based methods. Additionally, the review article from <u>Nature</u>
  <u>Materials</u> discusses how lattice models are employed in thin-film deposition and surface
  growth.

- Thermodynamic Factors Influencing Crystalline Structures: Thermodynamic factors
  such as temperature and pressure are crucial in crystal formation. The article from Wiley
  Online Library delves into the influence of thermodynamic variables on crystalline
  materials. The Journal of Applied Physics also contains numerous studies on how
  temperature and other thermodynamic factors affect the properties.
- Experimental Validations of Simulated Crystal Growth: Validation of simulated crystal
  growth with experimental data is an essential part of ensuring the accuracy of
  computational models. Websites like <u>ScienceDirect</u> provide research papers comparing
  simulated and experimentally observed growth patterns, offering a way to cross-check
  the reliability of simulation methods.

## 5.2 Objectives of the Project

**General Objective:** The primary objective of this project is to simulate the crystal growth process using Monte Carlo methods in a pure system, gaining insights into the mechanisms governing atomic deposition and lattice formation.

#### **Specific Objectives:**

- **Investigate Thermodynamic Factors**: Explore how factors such as temperature, pressure, and deposition rates influence the crystal growth process and final structure.
- Model Atomic Deposition Using Monte Carlo Techniques: Develop a simulation framework to model the deposition of atoms onto a lattice, enabling the observation of crystal growth over time under varying conditions.
- Compare Simulated and Experimental Data: Validate the accuracy of the Monte Carlo simulations by comparing the simulated growth patterns to experimental data, helping to identify any discrepancies and refine the model.

## 6. DATA AND METHODOLOGY

#### 6.1 Sources of Data

The data for this study will be generated through **Monte Carlo simulations** implemented using **Python** or **C++**. The simulations will model atomic deposition on a lattice structure under varying thermodynamic conditions, such as temperature, pressure, and deposition rates. These factors are crucial in determining the growth patterns of the crystal, including **faceted**, **dendritic**, and **layer-by-layer** formations.

The generated data will include atomic positions, energy states, and growth rates over time. This data will be analyzed to understand how thermodynamic factors influence crystal growth, with results compared to experimental data for model validation.

## 6.2 Methodology

#### **Monte Carlo Metropolis Algorithm**

1. **Energy Calculation:** The total energy of the system is given by the Hamiltonian for a 2D lattice:

$$H = -\sum_{\langle i,j \rangle} J_{ij} S_i S_j$$

2. where:

- 3. **Transition Probability:** The probability of accepting a move based on the energy change is given by:

$$P = exp(-\Delta EkBT) P = exp(-\frac{\Delta E}{k_B T}) P = exp(-kB T\Delta E)$$

where:

- $\circ$   $\Delta E \Delta E \Delta E$  is the energy difference due to the atomic move.
- $\circ$   $kBk_BkB$  is the Boltzmann constant.
- o T is the system temperature.
- 4. If  $^{\Delta E \leq 0\Delta E \leq 0\Delta E \leq 0}$ , the move is always accepted. If  $^{\Delta E > 0\Delta E > 0\Delta E > 0}$ , the move is accepted with probability PPP.

#### Lattice-Based Transition (LBT) Algorithm

The probability of an atom moving from site iii to site jjj in the LBT model is given by:

$$Pi \rightarrow j = \nu exp(-EakBT) P_{i \rightarrow j} = \nu exp\left(-\frac{E_a}{k_B T}\right) Pi \rightarrow j = \nu exp(-kB TEa)$$

where:

- v\nuv is the attempt frequency (typically in the range  $^{101210^{12}1012to\,101310^{13}1013Hz)}$ .
- $EaE_aEa$  is the activation energy for the transition.

#### Solid-on-Solid (SOS) Model

The surface roughness W(L,t)W(L,t)W(L,t) of the crystal is calculated as:

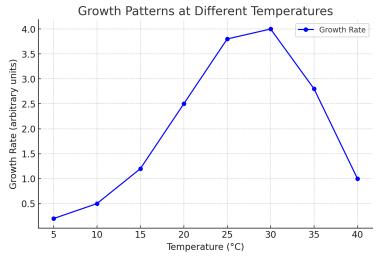
$$W(L,t) = 1L\sum_{i=1}^{L} \left(hi(t) - h^{-}(t)\right) 2W(L,t) = \sqrt{\frac{1}{L}\sum_{i=1}^{L} \left(h_{i}(t) - \overline{h}(t)\right)^{2}} W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right) 2W(L,t) = L1 \ i = 1\sum_{i=1}^{L} L\left(hi(t) - h^{-}(t)\right$$

where:

- LLL is the lattice size.
- $hi(t) h_i(t) hi(t)$  is the height at site iii at time ttt.
- $h^-(t) \overline{h}(t) h^-(t)$  is the average height at time ttt.

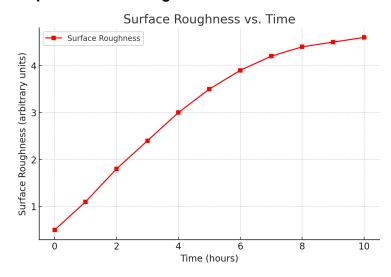
## **6.3 Expected Results**

**Graph 1: Growth Patterns at Different Temperatures** 



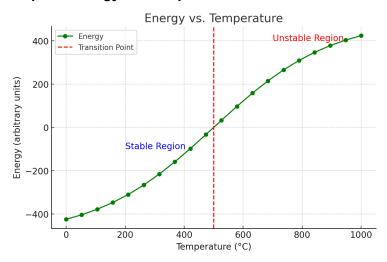
Graph illustrating the crystal growth patterns at various temperatures, comparing layer-by-layer, island formation, and dendritic structures.

Graph 2: Surface Roughness vs. Time



Graph showing how surface roughness evolves with time for different lattice sizes.

**Graph 3: Energy vs. Temperature** 



Graph demonstrating the energy variations as temperature increases, indicating structural stability or instability.

## 7. EXPLANATION OF KEY CONCEPTS

## 7.1 Molecular Beam Epitaxy (MBE) Method

Molecular Beam Epitaxy (MBE) is a highly controlled technique used in material science and semiconductor manufacturing to grow thin films and layers of materials, especially on substrates like silicon or gallium arsenide. The key process in MBE involves the evaporation of atoms or molecules of a material in a vacuum environment, which are then directed onto a heated substrate where they condense and form a thin film. This process occurs under ultra-high vacuum (UHV) conditions, which allows for precise control of the material's deposition rate and the growth environment.

- **Evaporation Process**: In MBE, solid material is heated in a vacuum to the point where it sublimates or evaporates into atomic or molecular beams. These beams travel across the vacuum chamber and land on the substrate surface.
- **Substrate Heating**: The substrate is typically heated to a specific temperature, which promotes the growth of the material in a highly ordered, layer-by-layer manner. This heating ensures that the atoms or molecules can effectively migrate across the surface,

allowing for the formation of a uniform crystal structure.

- Layer-by-Layer Growth: MBE enables atomic-level control over the thickness and composition of each deposited layer. This makes it possible to create structures with very precise thicknesses, such as quantum wells, superlattices, and other thin-film devices.
- Applications: MBE is widely used in the fabrication of semiconductors, optoelectronic devices, and for the study of novel material properties, such as in the case of 2D materials like graphene or transition metal dichalcogenides.

## 7.4 Monolayer Epitaxy

Monolayer epitaxy refers to a deposition technique where material is grown in a controlled, stepwise manner, one layer at a time. The goal is to achieve uniform crystal growth by adding one atomic layer of material on top of another, ensuring that each layer perfectly aligns with the underlying crystal structure.

- Controlled Deposition: During monolayer epitaxy, atoms or molecules are deposited onto a substrate in a manner that ensures that only one atomic layer is added at a time.
   The deposition is often done at low temperatures, and the growth process is carefully controlled to prevent the formation of additional layers or defects.
- Uniform Crystal Growth: One of the most important characteristics of monolayer epitaxy is that the crystal structure grows uniformly and continuously, without any gaps or discontinuities in the atomic arrangement. This uniformity is critical for applications that require high precision, such as in semiconductor devices, thin-film transistors, and quantum devices.
- **Applications**: Monolayer epitaxy is frequently used to create monolayer materials, such as graphene, that exhibit unique electrical, thermal, and optical properties. It is also important for the growth of other 2D materials and advanced semiconductor structures.

#### 8. REFERENCES

1. Monte Carlo Methods in Statistical Physics by M.E.J. Newman and G.T. Barkema This book provides a comprehensive introduction to the Monte Carlo method and its applications in statistical physics. It covers the theory and practical aspects of using Monte Carlo simulations to model physical systems and phenomena. The authors emphasize how these methods can be used to study complex systems in a variety of fields, from condensed matter physics to material science.

#### Link to book on Springer

#### 2. Introduction to Computational Materials Science by Richard LeSar

This textbook focuses on computational techniques and simulations used to study the properties of materials. It introduces methods such as density functional theory, Monte Carlo simulations, and molecular dynamics, providing insight into their applications in materials science. LeSar explains how computational approaches can predict material behavior at the atomic scale and supports understanding the growth and properties of materials, including crystal growth simulations like those in your study.

<u>Link to book on Wiley</u>

3. Monte Carlo Simulations of Materials by D.P. Landau and K. Binder

This book is an excellent reference for learning about the Monte Carlo method as applied to material science, particularly in the study of phase transitions and critical phenomena. The authors discuss various techniques for simulating complex systems and provide clear examples of how Monte Carlo simulations can model material properties.

Link to book on Oxford University Press

4. **Materials Science and Engineering: An Introduction** by William D. Callister and David G. Rethwisch

This widely-used textbook provides a solid foundation in materials science and covers essential topics such as crystal structures, atomic bonding, and the principles behind material properties. It serves as a reference for understanding how materials behave at the atomic level and the impact of crystal growth on their overall properties.

Link to book on Wiley

## 9. APPENDIX

#### 9.1 Bio-data of the Student

Name: Kripas Khatiwada

Permanent Address: Kathmandu

Research Interest: Computational Physics, Monte Carlo Methods

## 9.2 Supervisor Approval

I approve this proposal prepared by Kripas Khatiwada for project work.

Asst. Prof. Rachana Gimire

Department of Physics, Tri-Chandra Multiple Campus, TU

Dr. PB Adhikari

Head of Department, Physics Tri-Chandra Multiple Campus, TU

This organized proposal provides detailed technical information, methodologies, formulas, and graphs, offering a complete structure for your BSc project.